

United States Patent and Trademark Office

UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER FOR PATENTS P.O. Box 1450 Alexandria, Virginia 22313-1450 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO
10/616,799	07/10/2003	Byung Jin Choi	PA89/MII-56-38	2298
7590 03/21/2005		EXAMINER		
Kenneth C. Brooks			CULBERT, ROBERTS P	
Molecular Impr	rints, Inc.			
Legal Department		ART UNIT	PAPER NUMBER	
P.O. Box 81536			1763	
Austin, TX 78708-1536			DATE MAILED: 03/21/2005	

Please find below and/or attached an Office communication concerning this application or proceeding.

		Application No.	Applicant(s)			
		10/616,799	CHOI ET AL.			
Office Action Summary		Examiner	Art Unit			
		Roberts Culbert	1763			
The MA Period for Reply	ILING DATE of this communication app	pears on the cover sheet with the	correspondence address			
THE MAILING - Extensions of time after SIX (6) MON - If the period for re - If NO period for re - Failure to reply with Any reply received	D STATUTORY PERIOD FOR REPL DATE OF THIS COMMUNICATION. It may be available under the provisions of 37 CFR 1.1 ITHS from the mailing date of this communication. Ply specified above is less than thirty (30) days, a reply is specified above, the maximum statutory period thin the set or extended period for reply will, by statuted by the Office later than three months after the mailing adjustment. See 37 CFR 1.704(b).	36(a). In no event, however, may a reply be y within the statutory minimum of thirty (30) dwill apply and will expire SIX (6) MONTHS fro a cause the application to become ABANDON	timely filed ays will be considered timely. m the mailing date of this communication. IED (35 U.S.C. § 133).			
Status						
1) Respons	sive to communication(s) filed on 2/23.	/05.				
·	This action is FINAL . 2b) This action is non-final.					
3)☐ Since th	3) Since this application is in condition for allowance except for formal matters, prosecution as to the merits is					
closed in	accordance with the practice under b	Ex parte Quayle, 1935 C.D. 11,	453 O.G. 213.			
Disposition of Cla	aims					
4)⊠ Claim(s)	77-96 is/are pending in the applicatio	n.				
	e above claim(s) is/are withdra					
5) Claim(s)	is/are allowed.					
6)⊠ Claim(s)	77-96 is/are rejected.					
7) Claim(s)	is/are objected to.					
8) Claim(s)	are subject to restriction and/o	r election requirement.				
Application Pape	rs					
9)☐ The spec	ification is objected to by the Examine	er.				
10)☐ The draw	ring(s) filed on is/are: a)□ acc	epted or b) objected to by the	Examiner.			
Applicant	may not request that any objection to the	drawing(s) be held in abeyance. S	ee 37 CFR 1.85(a).			
Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).						
11) The oath	or declaration is objected to by the Ex	kaminer. Note the attached Offic	e Action or form PTO-152.			
Priority under 35	U.S.C. § 119		•			
	edgment is made of a claim for foreign)☐ Some * c)☐ None of:	priority under 35 U.S.C. § 119(a)-(d) or (f).			
1.☐ Ce	ertified copies of the priority document	s have been received.				
2.☐ Ce	ertified copies of the priority document	s have been received in Applica	tion No			
	opies of the certified copies of the prio	•	ved in this National Stage			
	plication from the International Bureau					
* See the at	tached detailed Office action for a list	of the certified copies not receive	ved.			
Attachment(s)			·			
1) Notice of Refere	nces Cited (PTO-892)	4) Interview Summar	y (PTO-413)			
2) Notice of Draftsp	erson's Patent Drawing Review (PTO-948) losure Statement(s) (PTO-1449 or PTO/SB/08)	Paper No(s)/Mail I	• •			
.S. Patent and Trademark Office PTOL-326 (Rev. 1-04)		ction Summary	Part of Paner No /Mail Data 0205			
10L-020 (116V. 1-04)	Office At	ction Summary	Part of Paper No./Mail Date 0305			

Art Unit: 1763

DETAILED ACTION

Response to Arguments

Applicant's arguments filed 2/23/05 with respect to claims 77, 82 and 87 have been considered but are most in view of the new ground(s) of rejection.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).

Claims 77, 79-82 and 84-96 are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent 5,534,073 to *Kinoshita et al.* in view of U.S. Patent 4,551,192 to *Di Milia et al.*

Referring to Figures 2 and 8 and the related disclosure (Col. 19, Line 46 – Col. 21, Line 23), Kinoshita et al. teaches a method of manufacturing a vacuum chuck comprising a chuck body (101) having first and second opposed surfaces comprising: forming a plurality of through holes (105) in a first surface and extending between first and second opposed surfaces and forming into the first surface a desired formation including a recess (125) having a nadir surface with one of the plurality of through holes disposed in the nadir surface.

Regarding Claims 77, 82 and 87, *Kinoshita et al.* does not explicitly teach that etching is used to form the desired formation including a recess in the first surface.

However, it is notoriously old and well known in the vacuum chuck art that recesses may be conveniently formed in vacuum chuck substrates by etching techniques. For example, *Di Milia et al.* teaches that a pattern may be formed in a vacuum chuck body by lithography (masking) and etching.

It would have been obvious to one of ordinary skill in the art at the time of invention to use etching as a means to form the desired formation including a recess in the first surface. One of ordinary skill in the art would have been motivated at the time of invention to use etching to form the pattern since lithography and etching techniques are well suited to forming patterns in vacuum chuck substrates as taught by Di Milla et al.

Regarding Claims 87, 92, and 95, *Kinoshita et al.* teaches that the cross-sectional area of the recess is greater than the cross-sectional area of the through holes. (See Figures 2 and 8, for example)

Regarding Claims 80, 85 and 89, *Kinoshita et al.* teaches that forming the recess further includes providing the recess with an annular shape. (See Figure 8)

Regarding Claims 81, 86 and 90, *Kinoshita et al.* teaches that forming the recess further includes forming a plurality of annular recesses, a subset of which includes one of the plurality of through holes.

(See Figure 8)

Regarding Claims 79, 84 and 88, *Kinoshita et al.* does not teach that the desired formation may include a plurality of pins disposed on the first surface.

However it is well known in the vacuum chuck art that a surface of a vacuum chuck may comprise either an annular pattern or a pattern of pins to support the substrate. Di Milia teaches the well-known pin-type formation (Figure 1.3)

It would have been obvious to one of ordinary skill in the art at the time of invention to etch a pintype formation to form a vacuum chuck in the manner taught by *Di Milia et al.* One of ordinary skill in the Application/Control Number: 10/616,799

Art Unit: 1763

art would have been motivated at the time of invention to use the pin-type formation since it minimizes the possibility of dust particles changing the substrate curvature. See *Di Milia et al.* (Col. 1, Lines 30-43)

Note that U.S. Patent 5,324,012 to Ayoama et al. cited in the previous Office Action also teaches the alternative annular and pin-type formations for vacuum chucks. (See Figures 1 and 3)

Regarding Claims 91, 93 and 96, Di Milia teaches that the first surface faces the substrate. (See Figure 2)

Claims 78 and 83 are rejected under 35 U.S.C. 103(a) as being unpatentable over U.S. Patent 5,534,073 to *Kinoshita et al.* in view of U.S. Patent 4,551,192 to *Di Milia et al.* as applied above to claims 77, 79-82 and 84-96 and in further view of U.S. Patent 5,515,167 to *Ledger et al.*

As applied above to claims 77, 79-82 and 84-96, *Kinoshita et al.* in view of *Di Milia et al.* teaches the method of the invention substantially as claimed but do not teach that the chuck body comprises an optical flat glass. However, it is old and well known in the vacuum chuck art that the surface of the chuck body should be extremely flat and have a finish of high optical quality. (See, for example, *Di Milia et al.* Col. 3, lines 33-38) The high degree of flatness ensures that a substrate is held flat against the chuck body.

Ledger et al. teaches that an optically flat glass substrate is suitable for the fabrication of vacuum chucks. (Col. 1, Lines 55-65 and Col. 3, Lines 53-55)

It would have been obvious to one of ordinary skill in the art at the time of invention to use an optically flat glass substrate to form the vacuum chuck. One of ordinary skill in the art would have been motivated at the time of invention to use an optically flat glass substrate to form the vacuum chuck in order to provide a highly flat surface that will not affect the substrate curvature and will further allow optical monitoring as taught by *Ledger et al.*

Note that Di Milia et al, Kinoshita et al, and Ledger et al. teach that the second surface of the vacuum chuck body is substantially flat.

Note also that *Ledger et al.* also teaches that various etching techniques are well suited to the formation of patterns in a glass vacuum chuck substrate. (Col. 3, Line 60 – Col. 4, Line 5)

Application/Control Number: 10/616,799

MONTHS from the date of this final action.

Art Unit: 1763

Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of

the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Roberts Culbert whose telephone number is (571) 272-1433. The examiner can normally be reached on Monday-Friday (8:30-5:00).

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Parviz Hassanzadeh can be reached on (571) 272-1435. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

R. Culbert

M. Collect

P. Hassonzadet SPE, AV 1767

Page 5